

QUARTZ GLASS AND QUARTZ GLASS JIG HAVING EXCELLENT
RESISTANCE AGAINST PLASMA CORROSION, AND METHOD FOR
PRODUCING THE SAME

ABSTRACT OF THE DISCLOSURE

An object of the present invention is to provide a quartz glass for
use as a jig material for plasma reaction in producing semiconductors
and a quartz glass jig, having excellent resistance against plasma
5 corrosion, particularly, excellent corrosion resistance against F-based
gaseous plasma; and a method for producing the same.

A quartz glass containing: a metallic element; and bubbles and
foreign matters at an amount expressed by projected area of less than
100 mm² per 100 cm³.